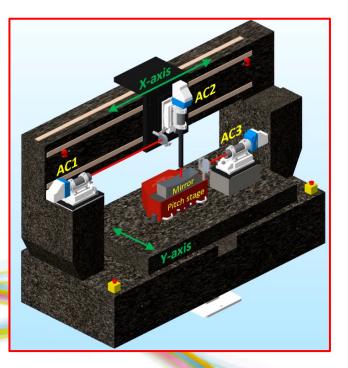
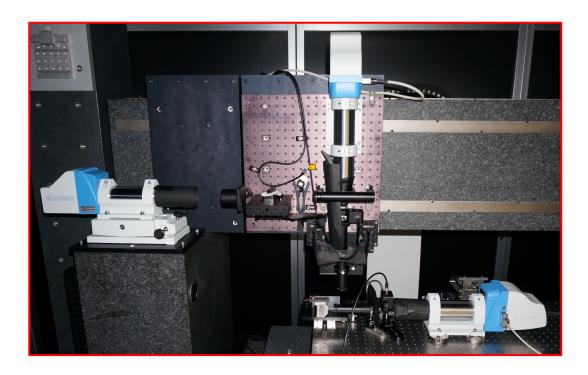
Diamond-VeNOM: a high-speed slope profiler for characterising X-ray mirrors





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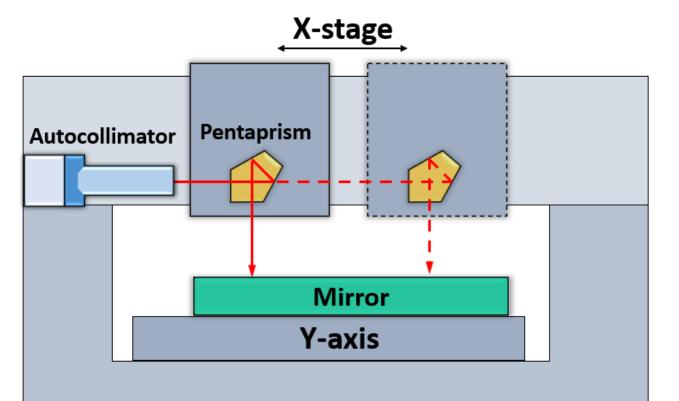


Need for high-quality optical metrology

- Many scientific communities, including synchrotron & XFEL light sources, require curved or flat optics beyond current state-of-the-art (slope errors < 50 nrad & height errors < 1 nm).</p>
- Deterministic correction of X-ray mirrors, such as EEM or IBF, requires accurate metrology data to guide polishing tool.
- Extensive work at many labs has created highly repeatable metrology instruments, including slope measuring profilers (LTP & NOM) & Fizeau- and micro-stitching interferometers.
- e As demands for optical quality increases, measurement errors becoming increasingly problematic.
- 8 How can we convert repeatability to accuracy? Calibration & minimisation of systematic errors
- New instrument: Diamond-VeNOM, an accurate, high-speed, slope profiler of X-ray mirrors



"Classical" NOM: scanning pentaprism



Elcomat3000 autocollimator (Moller Wedel) + pentaprism + granite air-bearings (Q-Sys)

- Diamond-NOM [1], operational since 2007, has measured 100's of X-ray substrates & mirror systems
- Step-scan or fly-scan with Elcomat3000 autocollimator (AC) acquisition @ 25 Hz
- Highly repeatable (<< 20 nrad)</p>
- Inspired by BESSY-NOM [2]
- Concept by von Bieren, Qian, Takacs, Lammert, Siewert, et al, since 1980's
- Successfully replicated at many labs, with extensive developments

[1] S.G Alcock et al, "Diamond-NOM: A non-contact profiler capable of characterizing optical figure error with sub-nanometre repeatability" <u>https://doi.org/10.1016/j.nima.2009.10.137</u> (2010). [2] F. Siewert et al, "Nanometer Optical Component Measuring Machine," in Modern Developments in X-Ray and Neutron Optics (Springer Berlin Heidelberg, 2008).



Instrument measurement errors

Random errors

> Reduced by acquiring multiple values (guided by statistical analysis).

Systematic errors

- > Environment (temperature, humidity, pressure): varying over hours and days
- > Path length (distance of mirror from AC)
- > Autocollimator's linearity errors: pixel-effect (~11 µrad) + other periods (~280 µrad)
- > Reflectivity & curvature of mirror under test
- > Location & size (& shape) of autocollimator beam-defining apertures
- > Parasitic angular errors of X-axis scan carriage
- > Pentaprism's polishing errors and/or misalignment
- Vibrations (< 1 sec)</p>
- > Air flow (seconds)
- Mechanical drifts

Ralf Geckeler et al "Environmental influences on autocollimator-based angle and form metrology", Rev. Sci. Instrum. 90, 021705 (2019) <u>https://doi.org/10.1063/1.5057402</u>

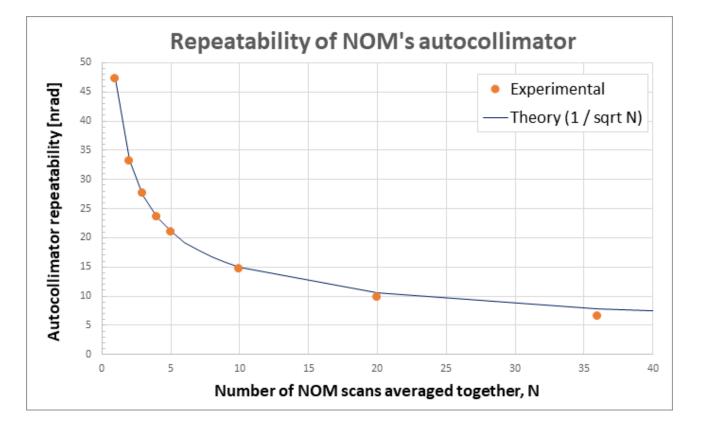
Error minimisation includes:

- > Thermal enclosure around instrument
- Humidity control
- Reduce stray light
- Acoustic damping
- High-quality optical components
- NMI calibration
- > Cross-comparison between instruments
- Round-robin measurements between labs



Random errors

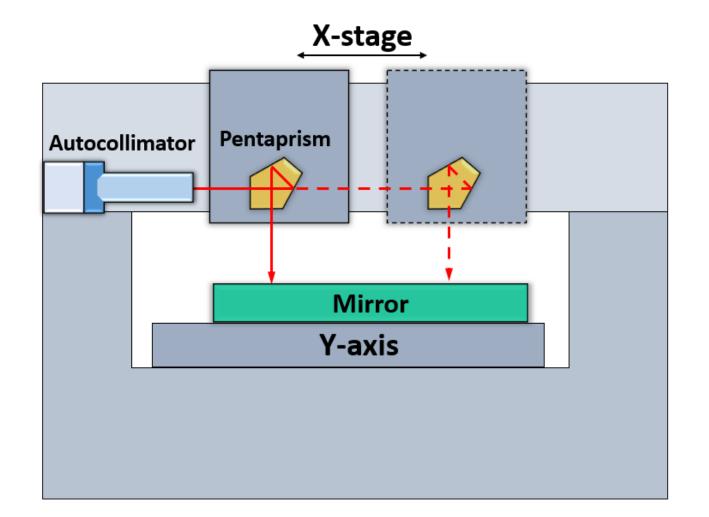
- Statistical studies show noise of Elcomat3000 autocollimator is random with a Gaussian (Normal) distribution
- Repeatability = difference between
 N scans averaged together and average of ensemble
- Oircles = AC measured data
- Line = 1/sqrt(N) relationship



Predicts number of scans to be averaged to reduce repeatability to given level (e.g. 20 scans averaged < 10 nrad)



Problems with "Classical" NOM



Problems

- Long, optical path length (> 1m) of AC beam is sensitive to environmental fluctuations
- > Variable path length of AC beam

Solutions

- > Small-angle generators for self-calibration
- NMI calibration of AC (but only for limited number of parameters)

Ralf D. Geckeler et al, "Distance-dependent influences on angle metrology with autocollimators in deflectometry," Proc. SPIE 7077, 70770B (2008) <u>https://doi:10.1117/12.793742</u>



Strategies to reduce systematic errors

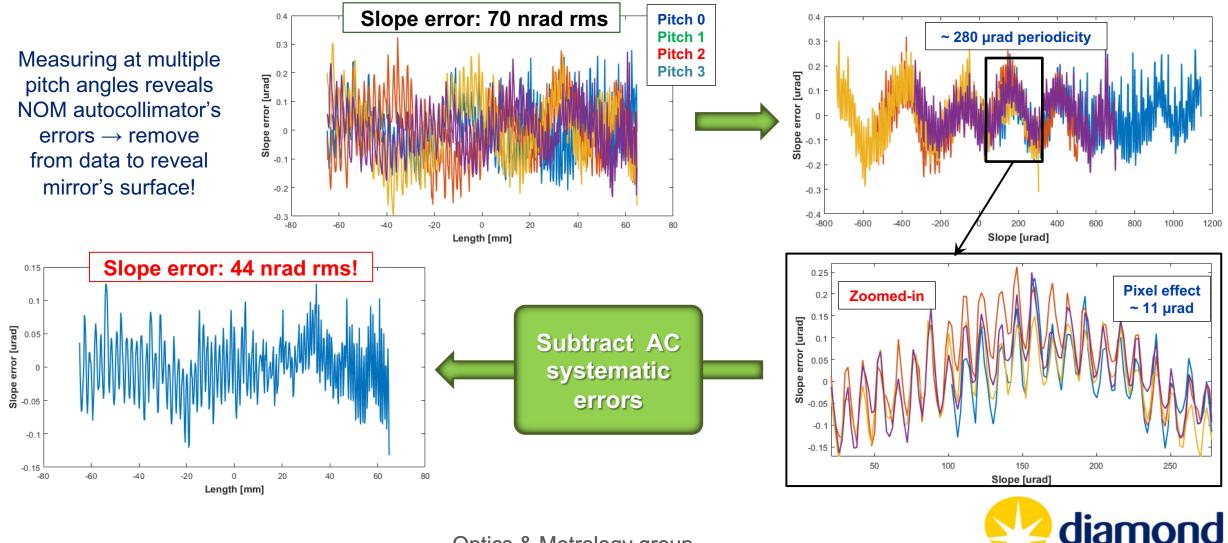
- Measure mirror in multiple configurations to change systematic errors
 - Vary path length of AC beam
 - > Flip mirror by 180 degrees (AB vs. BA), or use combinations AB & BA (Yashchuk *et al*)
 - > Pitch mirror: use different regions of AC's measurement range (pixel effect etc)
 - Change environmental conditions: add variable wait times between scans, or measure at different times of day, to vary influence of environmental periodicities (Yashchuk *et al*)
 - Monitor everything & compensate using NMI calibration of AC (e.g. PTB, Germany)
- Error reduction algorithms:
 - > Average: Sum different types of scans together to "average away" systematic errors
 - > Separate systematic errors from mirror's polishing marks:
 - L.E.E.P algorithm (Nicolas, Polack, Thomasset)
 - Angle shearing (Geckeler *et al*)

Works very well! But lots of scanning = lots of time



Measuring curved mirrors with slope errors < 50 nrad

Super-polished, strong ellipticity mirror from JTEC (160 mm long, R ~ 50 m) for I14 nano-probe beamline



Systematic errors: nearly 20 years later...

The Nanometer Optical Component Measuring Machine: a new Sub-nm Topography Measuring Device for X-ray Optics at BESSY

Frank Siewert, Tino Noll, Thomas Schlegel, Thomas Zeschke, and Heiner Lammert

Citation: AIP Conference Proceedings **705**, 847 (2004) doi: 10.1063/1.1757928 View online: http://dx.doi.org/10.1063/1.1757928

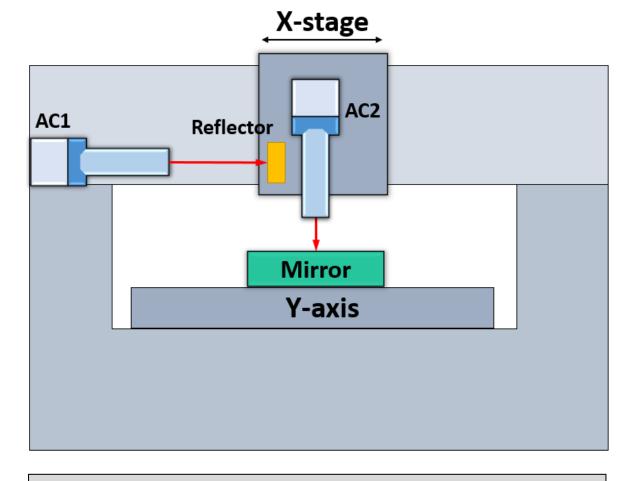
ENGINEERING CONCEPTION AND DESIGN OF THE NOM

The measurement uncertainty of the best surface measuring devices to day, like the Long Trace Profiler (LTP) [2] is limited to about 0.1 arcsec rms [3]. Only in special cases, could this 0.1 arcsec rms limit be improved [4]. The main problem is a multitude of systematic errors, which are not easily detected in the measurement result. To acquire a



Double AC setup

- To reduce path-length errors, & improve accuracy, double AC NOM's developed at Brookhaven & Lawrence Berkeley National Labs [3,4] + ?
- AC1 only sees small parasitic angles of Xaxis variations: less sensitive to path length changes
- Pixed path length for AC2 measuring optical surface ☑
- Reduces systematic errors, but doesn't address several systematic errors, including differences in reflectivity or curvature of mirror under test

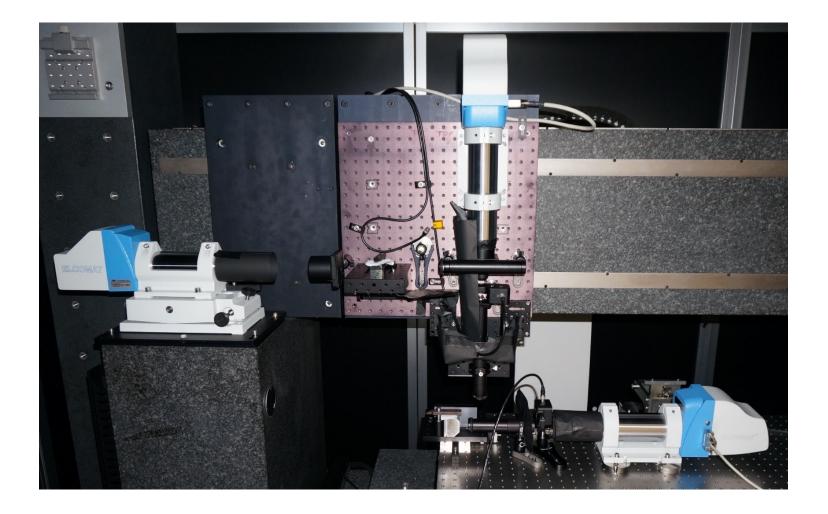


[3] Qian and Idir, "Innovative nano-accuracy surface profiler for sub-50 nrad rms mirror test," <u>https://doi.org/10.1117/12.2247575</u> (2016).
 [4] Lacey et al, "Development of a high performance surface slope measuring system for two-

dimensional mapping of x-ray optics," https://doi.org/10.1117/12.2273029 (2017).



Diamond-VeNOM (velocity-NOM)

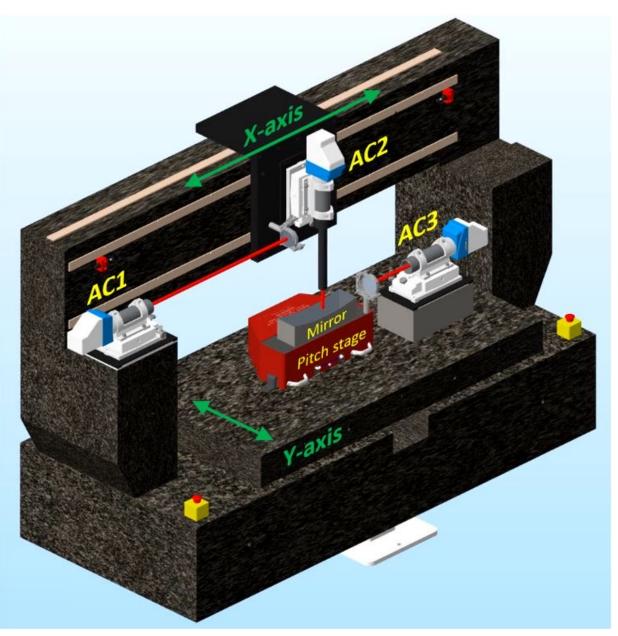


New VeNOM concept

- Freeform motion of translation stage, synchronized with dynamic pitch changes of test optic DURING scanning
- All motion synchronised with autocollimator data via triggered shutters
- Combines metrology benefits of previous schemes & provides many new possibilities!



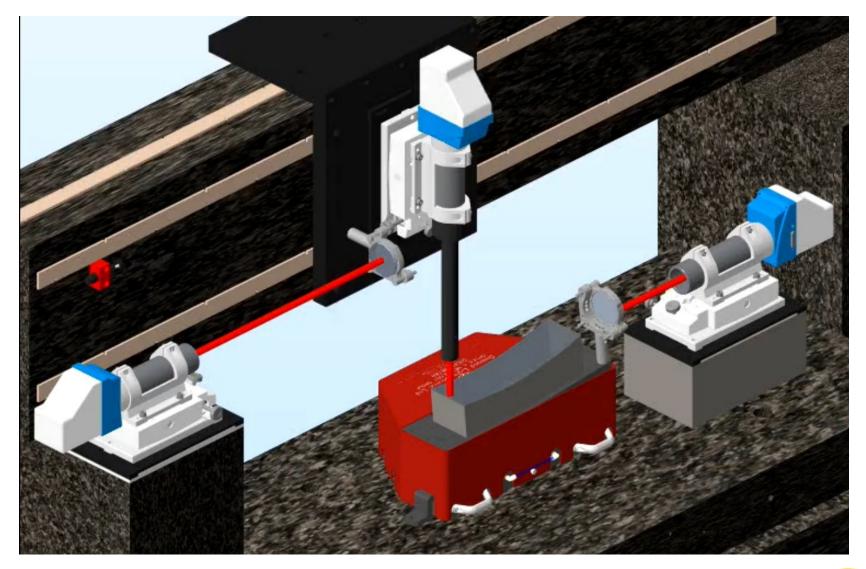
Diamond-VeNOM (velocity-NOM)



- Mirror under test placed on a motorized pitch stage which moves **DURING** scan
- AC1: mounted on side pillar, monitors parasitic angles during freeform motion of X-stage
- AC2 (Elcomat 5000): mounted on X-stage, directly measures optical surface
- AC3: monitors angle of a reflector located on motorized pitch stage



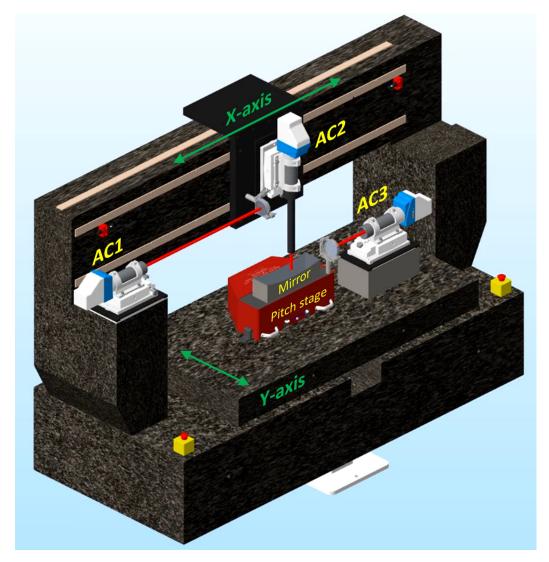
Diamond-VeNOM (velocity-NOM)





Improved accuracy

- AC1 = flat mirror on X-axis stage. Angles ~ few microrad, so length-dependent issues (affects single AC + pentaprism) are minimized
- AC2 = mirror under test & calibrated for fixed distance. Optical surface is continuously nulled for each measurement point. Systematic errors from curvature or reflectivity are negligible for small angles measured
- AC3 = flat mirror on pitch stage. Observes large angles, but always measures same flat mirror under fixed conditions (distance, curvature, reflectivity & larger aperture). Can be calibrated for this specific case at NMI





New hardware for VeNOM

Synchronization rates required for VeNOM cannot be supported by NOM's old instrumentation hardware



New PMAC Power Clipper controller for NOM's motion stages (Q-Sys)



PandA box acquisition & control system (encoder inputs & triggers fast mechanical shutters)



New Elcomat5000 autocollimator: 10x faster acquisition @ 250Hz



MOXA box serial server



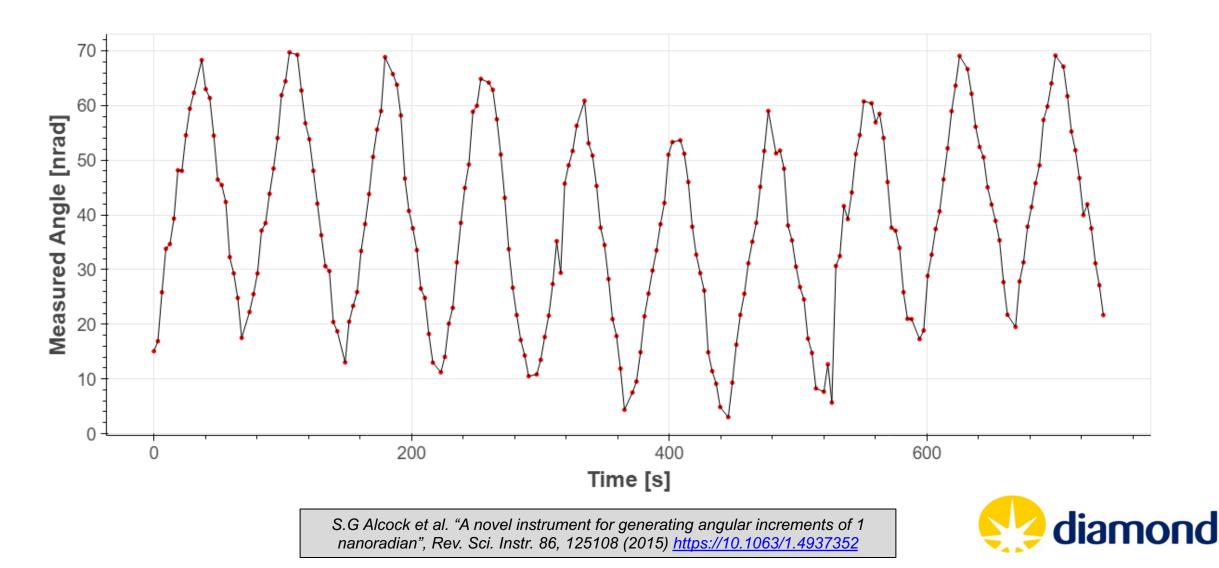


Electro-mechanical rotary shutters (Thorlabs SH-05)



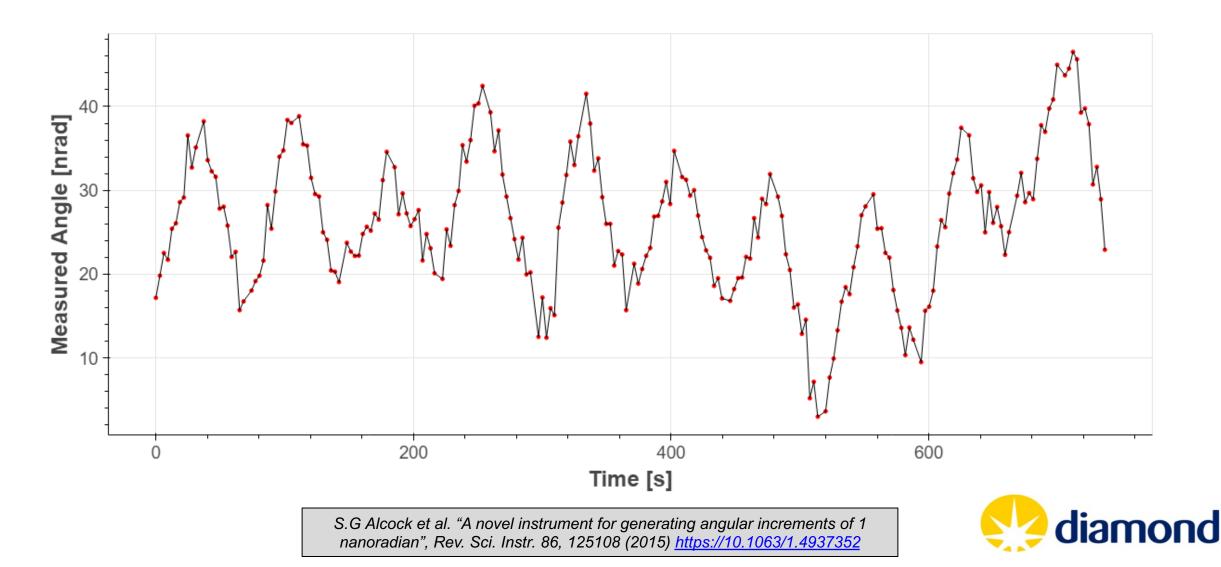
Elcomat5000 performance: 5 nrad steps

Stair-case of ultra-small angle steps (generated by Diamond-NANGO) as viewed by E5k

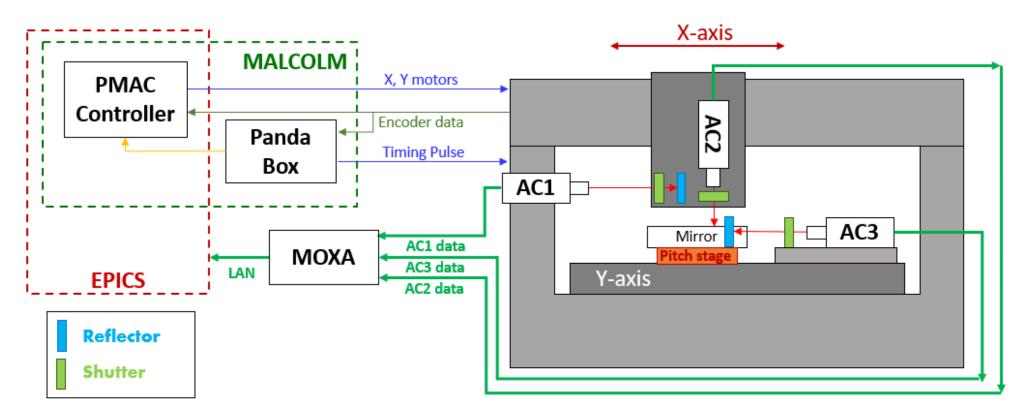


Elcomat5000 performance: 2 nrad steps!!!

Stair-case of ultra-small angle steps (generated by Diamond-NANGO) as viewed by E5k



Co-ordination between X-axis, pitch stage & ACs



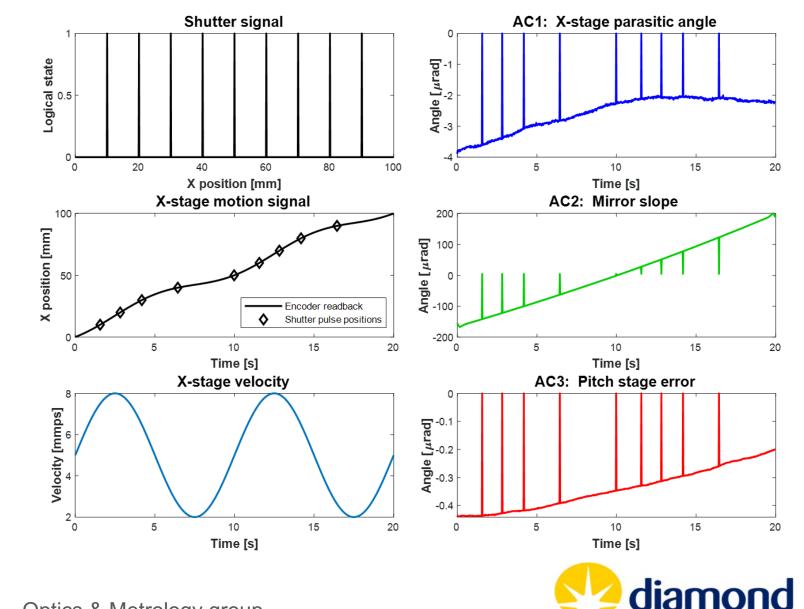
- New power PMAC controller + PandA I/O box → synchronisation of motion stages & shutters, via Malcolm framework & Mapping Project
- Powerful & adaptable UI with python scan & analysis scripts (enhanced automation & metadata logging)

Enables dynamic, freeform trajectories for motion axes: Position, Velocity, Time (PVT)



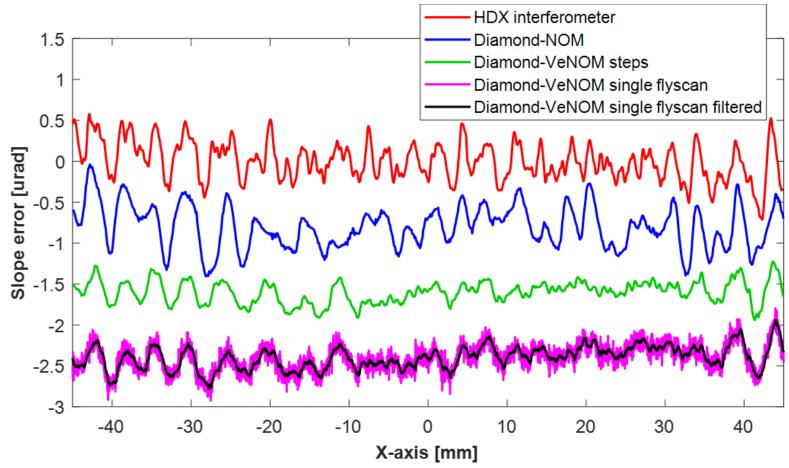
Data synchronisation

- Shutters triggered once translation and/or pitch stage reach user-defined positions and/or angles
- Null values embedded within autocollimator data stream align with motion trajectories & location on optical surface



Optics & Metrology group

Cross-comparison

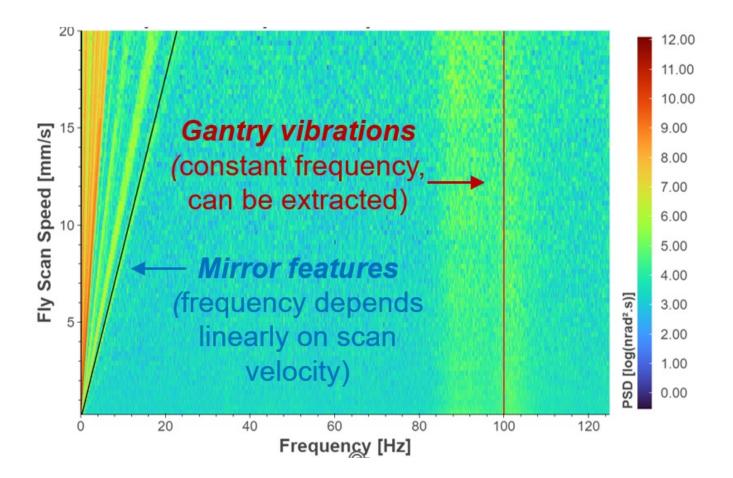


- 9 Good agreement between instruments for 100 nrad X-ray mirror with elliptical profile
- Spatial filtering of single fly-scan in close agreement with average of multiple fly-scans

10x faster AC & fly-scan operation \rightarrow 30 seconds / measurement!



Separating polishing marks from vibrations / noise



Concept

- Fly scan @ 80 different speeds
- Calculate PSD of measured AC angle as function of time (1/f)
- Plot Power Spectral Density (PSD) versus frequency & scan speed

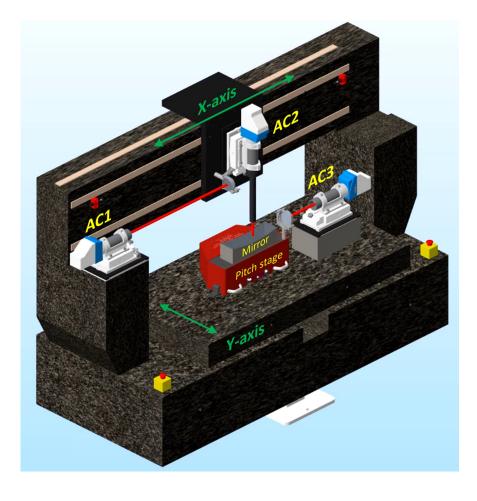
- Mirror's surface information: spreads linearly as speed increases
- Vibrations of NOM's gantry: constant frequency



Dynamic nulling of optical surface

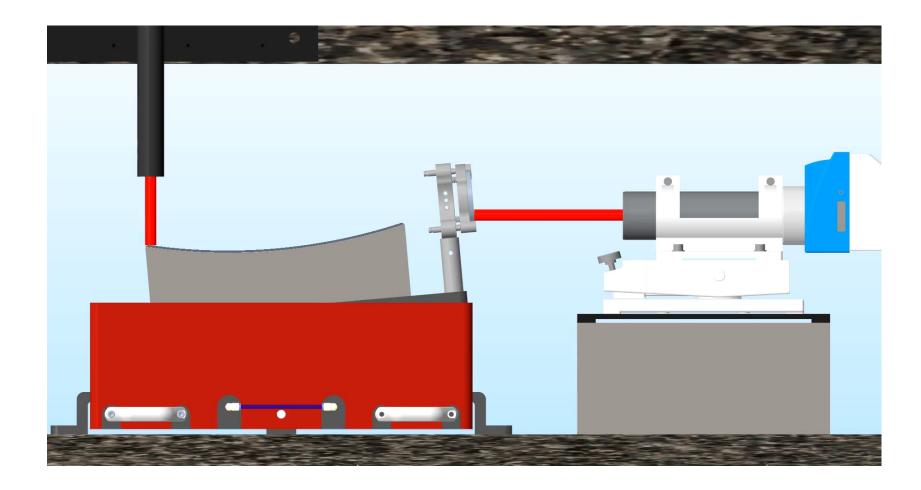
Angle measured by AC2 is function of position (X-axis) & time:

- $\theta_{AC2}(x, t) = Mirror's slope profile (x)$
 - + Mirror's slope errors (x)
 - + Parasitic angle of X-stage (x)
 - + Pitch angle of goniometer (t)
 - + AC's linearity errors (θ_{AC2})
 - + Vibrations (t)
 - + Mechanical & environmental drifts (t)





Dynamic nulling of optical surface



- Principle: minimise angle seen by AC2 (to reduce systematic errors due to curvature, reflectivity, etc)
- Velocity of X-stage & pitch rate chosen to match mirror's slope profile



Dynamic nulling of optical surface

- . Can set θ_{AC2} (x, t) ~ 0 throughout scan by careful choice of X-axis speed + pitch stage angle rate
 - Cylinder null = constant velocity for X axis + constant rate of angle change for pitch stage
 - Ellipse null = variable velocity for X axis (elliptical profile) + constant rate of angle change for pitch stage
 - [Ellipse null + correction of pitch stage's linearity errors = add perturbation to variable velocity for X-axis]
- On the second second



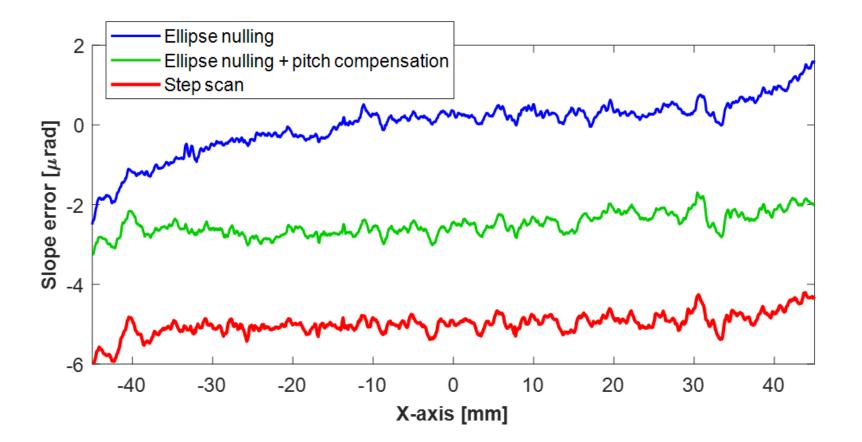
ADVANCED: beyond nulling of optical surface!

- Deterministically add angles to nulled measurement to purposefully change experiment during or between each scan:
 - > Null the effects of slow-variations in environment (logged by weather station)
 - > Apply LEEP algorithm (offset pitch angle) DURING scan
 - Move through specific sections of AC2's measurement range (and/or AC3) to apply an "anti-pixel effect" (or cancel other pseudo-periodicities such as ~ 280 µrad)
 - Apply analytical functions to slope profile (sine wave or chirp) which can be more efficiently extracted ("lock-in" principle)
 - > Any crazy ideas to break time, spatial, or angle-dependent symmetries! ©

In the past, with a fixed curvature mirror, you only had a single slope profile to measure. Now you can now controllably apply any slope profile you want!!!



Experimental: nulling an elliptical profile



Slope measured during nulled fly-scan

Slope measured during nulled fly-scan after compensating for pitch rate errors of goniometer

Slope error measured by step scan with no nulling

To ensure that AC2 sees zero angle (to minimise systematic errors), linear velocity of X-axis & angular velocity of pitch stage were co-ordinated to null elliptical slope profile of 100 nrad X-ray mirror

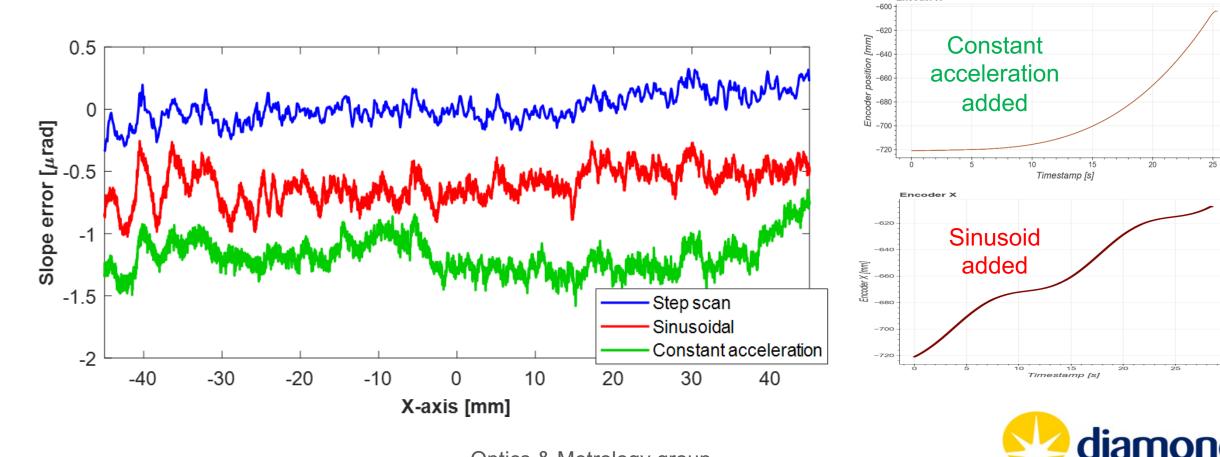


Experimental: Deterministic trajectories

9 Deterministically add sinusoid or constant acceleration to nulled measurement of 50 nrad X-ray mirror

Encoder X

- 🔮 Principle proven 🗹
- 🥺 Further commissioning & development 😊



Summary

- Diamond-VeNOM: fast & versatile slope profilometer utilising multiple ACs with 250 Hz acquisition
- Combines advantages of several previous schemes
- Adds a new concept: freeform, dynamic scanning of the mirror, including pitching the mirror DURING scan!
- All motions synchronised with autocollimator data via triggered shutters
- Reduced systematic errors to improve accuracy
- Ply-scanning, combined with speed enhancement of new autocollimators, leads to a 20X time efficiency of VeNOM compared to Diamond-NOM, without loss of data quality
- VeNOM can accurately measure a 100 nrad mirror in 30 seconds using "Super-fly"!



Acknowledgements

- Emilio Perez-Juarez & Adam Howell (Diamond EPICS & Python scripts)
- Brian Nutter & Nico Rubies (Diamond Motion controls)
- Andy Malandain (Diamond Mech. Tech.)
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